



PATENT  
Customer No. 22,852  
Attorney Docket No. 04329.3161

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
KENJI KAWANO ET AL. )  
Application No.: 10/682,419 ) Group Art Unit: 2812  
Filed: October 10, 2003 ) Examiner: Tran, Mai Huong C.  
For: METHOD OF PROCESSING A ) Confirmation No. 3440  
SUBSTRATE, HEATING )  
APPARATUS, AND METHOD OF )  
FORMING A PATTERN )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO RESTRICTION REQUIREMENT**

In a restriction requirement mailed November 9, 2004, the period for response extending through January 9, 2005, by virtue of the attached Petition for Extension of Time, the Examiner required restriction under 35 U.S.C. § 121 between Group I, claims 26-39, characterized by the Examiner as drawn to a semiconductor device (class 257, subclass 642); and Group II, claims 1-25 and 40-52, characterized by the Examiner as drawn to a semiconductor device (class 438, subclass 781). Applicants elect to prosecute Group I, claims 26-39.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

By: *Richard V. Burgujian*  
*Richard V. Burgujian* #27,432  
Richard V. Burgujian  
Reg. No. 31,744

Dated: January 6, 2005